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Oliver Brand received his diploma degree in Physics from Technical University Karlsruhe, Germany in 1990, and his Ph.D. degree (Doctor of Natural Sciences) from ETH Zurich, Switzerland in 1994. From 1995 to 1997, he worked as a postdoctoral fellow at Georgia Tech. From 1997 to 2002, he was a lecturer at ETH Zurich in Zurich, Switzerland and deputy director of the Physical

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Publications - Georgia Institute of Technology
CMOS cantilever sensor systems: atomic-force microscopy and gas sensing applications. D Lange, O Brand, H Baltes, H Baltes. Springer Science & Business Media, 2002. 84: 2002: Metal oxide-based monolithic complementary metal oxide semiconductor gas sensor microsystem.